



**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

Form PTO-1449 (Modified)
(Use several sheets if necessary)

COMPLETE IF KNOWN

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| Application Number | 10/631,376 |
| Confirmation Number | 2135 |
| Filing Date | July 30, 2003 |
| First Named Inventor | Eric J. BERGMAN |
| Group Art Unit | 1746 |
| Examiner Name | |
| Attorney Docket No. | 54008.8033.US00 (P03-0004) |

Sheet 1 of 5

U.S. PATENT DOCUMENTS

| Examiner Initials* | Cite No. | U.S. Patent or Application | | Name of Patentee or Inventor of Cited Document | Date of Publication or Filing Date of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
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EXAMINER

EL-Arini

DATE CONSIDERED

11/15/04

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[54008.8033.US00/LA041610.014]

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| ZE | BT | Amick, J.A., "Cleanliness and the Cleaning of Silicon Wafers." <i>Solid State Technology</i> , pp. 47-52 (Nov. 1976). | |

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| | BW | Bedge, S., <i>et al.</i> , "Kinetics of UV/O ₂ Cleaning and Surface Passivation: Experiments and Modeling." <i>Mat. Res. Soc. Symp. Proc.</i> , 259:207-212 (1992). | |
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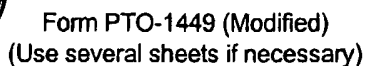
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| | CI | Kasi, S., <i>et al.</i> , "Vapor phase hydrocarbon removal for Si processing." <i>Appl. Phys. Lett.</i> , 57(20):2095-2097 (Nov. 1990). | |
| | CJ | Kern, W., "The Evolution of Silicon Wafer Cleaning Technology." <i>J. Electrochem. Soc.</i> , 137(6):1887-1892 (Jun. 1990). | |
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| | CS | Tong, J., <i>et al.</i> , "Aqueous Ozone Cleaning of Silicon Wafers." <i>ECS Extended Abstracts</i> , Phoenix, AZ, Abstract No. 506, pp. 753 (Oct. 13-17, 1991). | |
| | CT | Tong, J., <i>et al.</i> , "Aqueous Ozone Cleaning of Silicon Wafers." <i>Proc. of 2.sup.nd Int'l. Symposium on Cleaning Tech. In Semiconductor Device Mfg.</i> , pp. 18-25 (Oct. 1992). | |
| | CU | Vig, J., "UV/Ozone Cleaning of Surfaces." <i>U.S. Army Elec. Tech. and Devices Lab.</i> , pp. 1-26. | |
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| | CW | Vig, J., <i>et al.</i> , "UV/Ozone Cleaning of Surfaces." <i>IEEE Transactions on Parts, Hybrids, and Packaging</i> , Vol. PHP-12(4):365-370 (Dec. 1976). | |
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| ZE | DB | "Ozone for Semiconductor Applications." <i>Sorbios</i> , pp. 1-6 (Oct. 1991). | |

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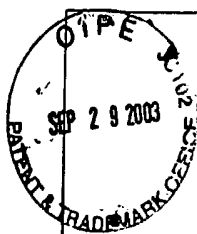
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